

PATENT

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Serial No.: 10/711,649
Applicant: Kawamura et al.
Title: **METHOD FOR SUPERCRITICAL CARBON DIOXIDE
PROCESSING OF FLUORO-CARBON FILMS**
Attorney Docket: SSIT-114
Confirmation No.: 5648

Cincinnati, OH

June 7, 2006

Mail Stop Amendment
Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

RESPONSE TO OFFICE ACTION

This paper is responsive to the Office Action mailed March 7, 2006. The Examiner has indicated that claims 1-26 are pending in the application and rejected. The present response includes the following:

Amendments to the Specification:	Page 2
Amendments to the Claims:	Pages 3-7
Amendments to the Abstract:	None
Amendments to the Drawings:	None
Remarks:	Pages 8-11
Attachments:	None